

ABSTRACT OF THE DISCLOSURE

A method for manufacturing a probe card comprises the steps of forming a plurality of amorphous alloy layers of a predetermined shape at a predetermined substrate, wherein the amorphous alloy layer has a supercooled liquid temperature area, heating the amorphous alloy layer at the supercooled liquid temperature area, cooling the amorphous alloy layer at a temperature lower than the supercooled liquid temperature area and removing at least a part of the substrate in a state where the amorphous alloy layer is cooled at a temperature lower than the supercooled liquid temperature area.